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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)			
Lee		Murakami, M. et al, <i>Thermally stable, low-resistance NiInW ohmic contacts to n-type GaAs</i> , Appl. Phys. Lett. 51 (9), 31 Aug. 1987, pp. 664-666.	
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Lee		Jan, C., et al, <i>Alloying of Ni/In/n-GaAs ohmic contacts induced by Ga-Ni-As ternary eutectic reactions</i> , J. Appl. Phys. 68 (12), 15 Dec. 1990, pp. 6458-6462.	
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